



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)

Helen H. ZHU et al.)

Application No.: 09/820,694)

Filed: March 30, 2001)

For: METHOD OF PLASMA ETCHING)
SILICON NITRIDE)

Group Art Unit: 2823

Examiner: J. J. Maldonado

Confirmation No.: 7374

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated June 9, 2004, please amend the
above-identified application as follows:

10/14/2004 BSAYASI1 00000115 024800 09820694

01 FC:1251 110.00 DA
02 FC:1202 108.00 DA